"GAS EXCITATION DEVICE"

ABSTRACT

This excitation device, in particular for surface-treatment gases, includes a gas excitation chamber (20) provided with a gas inlet passage (28) in communication with a primary gas supply source (36), and an outlet passage (30) for excited gas. It includes a venturi-effect constriction (34) arranged on the path of the gas between the primary gas supply source (36) and the said inlet passage (28). It furthermore includes at least one secondary gas supply source (32) in communication with a region located downstream of the constriction (34), the gas delivered by the said secondary source (32) being entrained by venturi effect into the excitation chamber (20).

Fig. 1